

## Integrated Systems Nanofabrication Cleanroom (ISNC) Personnel

**KRISSY DO (B.S)** serves as a Junior Development Engineer, handling both administrative and technical tasks. Her administrative responsibilities include billing, management of student workers, day to day clean room operations, and supply inventory management. In order to ensure safe and efficient use of facilities, Krissy also leads safety protocol trainings for new users. On the technical side, she operates a number of the machines SVG Track Coater, furnaces, etc. and is in charge of the Metallization and some of the Metrology services.

Contact: [krissydo@cnsi.ucla.edu](mailto:krissydo@cnsi.ucla.edu) / (310) 983-3253

**YUWEI FAN (Ph.D.)** serves as a Sr. Development Engineer where she is the primary engineer for Ebeam Lithography tool, Scanning Electron Microscope (SEM), Atomic Force Microscope (AFM), and CDSEM as well as Maskless patterning tool. Yuwei has over 15 years of experience in nanofabrication and ebeam lithography experience, starting with her work on carbon nanotube sensors and photoelectronic transport imaging at Max-Planck-Institute and as a postdoc and specialist at UCI and UCLA. Yuwei's extensive experience in device design, fabrication and characterization allows her to provide consultation and support for ISNC Users as well as the cleanroom foundry projects.

Contact: [fan@cnsi.ucla.edu](mailto:fan@cnsi.ucla.edu) / (310) 983-3257

**ADAM STIEG (Ph.D.)** serves as the Associate Director of Shared Resources, Scientific Director of the Nano and Pico Characterization Core Facility and Interim Technical Director of the ISNC. At CNSI, Adam is responsible for development and implementation of operational models for effective utilization of UCLA resources; providing counsel on behalf of the Core Laboratories and their staff to the CNSI Director; serving as a liaison to the CNSI membership; and representation of the CNSI Core Labs at various symposia, conferences and meetings. In the ISNC, he oversees the ongoing management and operations of the user facility, providing consultation services for prospective users, and pursuit of funding opportunities toward the acquisition of new instrumentation.

Contact: [stieg@cnsi.ucla.edu](mailto:stieg@cnsi.ucla.edu) / (310) 206-2902

**LORNA TOKUNAGA (M.S.)** serves as Senior Development Engineer responsible for ASML Stepper, Tystar Furnaces, Wet Processing, Operations/Safety Documentation, Orientation, Foundry Project Management (traveler preparation/process integration) and 2<sup>nd</sup> Shift ISNC Staff Coverage. Lorna has over 25 years of industry experience (Xerox Corp, TRW Inc, International Rectifier Corp) as process engineer/manager for Atmospheric & LPCVD Furnaces, PECVD & Epitaxial Silicon Deposition, Wet Processing and Process Development/Integration.

Contact: [lornat@cnsi.ucla.edu](mailto:lornat@cnsi.ucla.edu) / (310) 983-3413

**TONY WRIGHT** serves as an Equipment Engineer responsible for the maintenance, installation and repair of process equipment and facilities. Additionally, Tony provides training and user assistance on ISNC equipment including: Tony has over 30 years of experience in industry (TRW, M/A-Com, Electromask) prior to joining the ISNC team.

Contact: [tonywright@cnsi.ucla.edu](mailto:tonywright@cnsi.ucla.edu) / (310) 983-1182